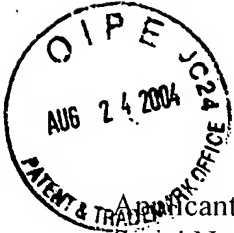


IFW

Attorney's Docket No.: 008114-539001



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Jeffrey Drue David

Art Unit : 3723

Serial No. : 10/643,583

Examiner : Unknown

Filed : August 18, 2003

Title : PLATEN AND HEAD ROTATION RATES FOR MONITORING CHEMICAL MECHANICAL POLISHING

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

PRELIMINARY AMENDMENT

Prior to examination, please amend the application as indicated on the following pages.

CERTIFICATE OF MAILING BY FIRST CLASS MAIL

I hereby certify under 37 CFR §1.8(a) that this correspondence is being deposited with the United States Postal Service as first class mail with sufficient postage on the date indicated below and is addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

Date of Deposit August 19, 2004

Signature

Typed or Printed Name of Person Signing Certificate

Nikia M. Mc Nillion